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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/980,754	02/15/2002	Wilfred Lerch	Az. 2964	7497
30996 7:	590 07/15/2003			
ROBERT W.	BECKER & ASSOC	CIATES	EXAM	INER
707 HIGHWAY 66 EAST SUITE B			MALDONADO, JULIO J	
TIJERAS, NM	87059		ART UNIT	PAPER NUMBER
		•	2823	
			DATE MAILED: 07/15/2003	

Please find below and/or attached an Office communication concerning this application or proceeding.

•			m		
	Application No.	Applicant(s)			
	09/980,754	LERCH ET AL.			
Office Action Summary	Examiner	Art Unit			
TI MANUAL DATE SALE	Julio J. Maldonado	2823			
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the (correspondence address :			
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.1: after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period v - Failure to reply within the set or extended period for reply will, by statute - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b). Status	36(a). In no event, however, may a reply be ting within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	mely filed /s will be considered timely. In the mailing date of this communication (35 U.S.C. § 133).	ation.		
1) Responsive to communication(s) filed on 09 A	<u> April 2003</u> .				
2a)☐ This action is FINAL. 2b)⊠ Th	is action is non-final.				
3) Since this application is in condition for allowated closed in accordance with the practice under			its is		
Disposition of Claims	par.co queyre,				
4) Claim(s) 28-50 is/are pending in the application	on.				
4a) Of the above claim(s) is/are withdraw	wn from consideration.				
5) Claim(s) is/are allowed.					
6)⊠ Claim(s) <u>28-50</u> is/are rejected.					
7) Claim(s) is/are objected to.					
8) Claim(s) are subject to restriction and/o	r election requirement.				
Application Papers					
9) The specification is objected to by the Examiner.					
10) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner. Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).					
11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.					
If approved, corrected drawings are required in reply to this Office action.					
12)☐ The oath or declaration is objected to by the Examiner.					
Priority under 35 U.S.C. §§ 119 and 120					
13) Acknowledgment is made of a claim for foreign	n priority under 35 U.S.C. § 119(a)-(d) or (f).			
a)☐ All b)☐ Some * c)☐ None of:					
1.☐ Certified copies of the priority document	s have been received.				
2. Certified copies of the priority document	s have been received in Applicat	ion No			
Copies of the certified copies of the prio application from the International Bu See the attached detailed Office action for a list	reau (PCT Rule 17.2(a)).				
14) Acknowledgment is made of a claim for domesti	c priority under 35 U.S.C. § 119	(e) (to a provisional applic	cation).		
a) The translation of the foreign language pro	• •				
Attachment(s)	_				
1) 🔀 Notice of References Cited (PTO-892) 2) 🔲 Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) 🔲 Information Disclosure Statement(s) (PTO-1449) Paper No(s) _	5) Notice of Informal	y (PTO-413) Paper No(s) Patent Application (PTO-152)	<u> </u>		
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DETAILED ACTION

- 1. Claim 50 is newly added.
- 2. Claims 28-50 are pending in this application.

Continued Examination Under 37 CFR 1.114

3. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 05/12/2003 has been entered.

Claim Rejections - 35 USC § 112

- 4. The following is a quotation of the first paragraph of 35 U.S.C. 112:
 - The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.
- 5. Claims 28-50 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the written description requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to reasonably convey to one skilled in the relevant art that the inventor(s), at the time the application was filed, had possession of the claimed invention. Independent claims 28 and 50 claim a two step process, in which the first step comprises controlling the distribution of foreign atoms as a function of a process gas atmosphere and in which the second step comprises forming either a silicon nitride layer or a silicon oxynitride layer. However,

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to. to.

according to the specification, the distribution of foreign atoms is controlled by the thickness of either silicon nitride or silicon oxynitride formed over the surface of the substrate. In the same manner the thickness of either the silicon nitride or the silicon oxynitride layer is controlled by the concentration of gases during the formation of the silicon nitride or silicon oxynitride layer. Therefore, the distribution of foreign atoms is controlled by the concentration of gases used in the formation of the silicon nitride or the silicon oxynitride layer, which is a one-step process, not a two-step process.

Conclusion

6. Papers related to this application may be submitted directly to Art Unit 2823 by facsimile transmission. Papers should be faxed to Art Unit 2823 via the Art Unit 2823 Fax Center located in Crystal Plaza 4, room 3C23. The faxing of such papers must conform to the notice published in the Official Gazette, 1096 OG 30 (15 November 1989). The Art Unit 2823 Fax Center number is (703) 305-3432. The Art Unit 2823 Fax Center is to be used only for papers related to Art Unit 2823 applications.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to **Julio J. Maldonado** at **(703) 306-0098** and between the hours of 8:00 AM to 4:00 PM (Eastern Standard Time) Monday through Friday or by e-mail via <u>julio.maldonado@uspto.gov</u>. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri, can be reached on (703) 306-2794.

Any inquiry of a general nature or relating to the status of this application should be directed to the **Group 2800 Receptionist** at **(703) 308-0956**.

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JMR 7/11/03

George Fourson
Primary Examiner